

BIBLIOGRAFÍA

- [1] M. Stanley Livingston, John P. Blewett. Particle Accelerators, Mc Graw-Hill, Book Company, INC. N.Y 1962.
- [2] E. Persico, E. Ferrari, S.E. Segre. Principles of Particle Accelerators, W.A. Benjamin, INC.N.Y 1968.
- [3] H. Bruck, Accélérateurs circulaires de particules, Presses Universitaires de France, Paris 1966.
- [4] B.W. Montague, RF acceleration, Proceedings of the first Course of the International School of Particle Accelerators, ERICE – CERN 77–13, 19 July 1977.
- [5] M. Sands, The physics of electron storage rings, SLAC report 121 (1970).
- [6] Varena 1969, Academic Press, N.Y. 1971.
- [7] D. López, R.S. Decca, E. Fischbach, D.E. Krause, “MEMS-Based Force Sensor: Design and Applications”, Bell Labs Technical Journal, vol. 10, no. 3, 2005.
- [8] J.J. Yao, “RF MEMS from a device perspective”, Journal of Micromechanics and Microengineering, vol. 10, 2000.
- [9] Wong, H. Ding, C. T.-C. Nguyen, “Micromechanical Mixer+Filters”, IEEE International Electron Devices Meeting, IEDM’98 Technical Digest, 1998.
- [10] E. Verpoorte, N.F. De Rooij, “Microfluidics Meets MEMS”, Proceedings of the IEEE, vol. 91, no. 6, 2003.
- [11] T. Thundat, G.Y. Chen, R.J. Warmack, D.P. Allison, E. A. Wachter, “Vapor Detection Using Resonating Microcantilevers”, Analytic Chemistry, vol. 67, 1995.
- [12] A. Bosseboeuf, S. Petitgrand, “Characterization of the static and dynamic behaviour of M(O)EMS by optical techniques: status and trends”, Journal of micromechanics and microengineering, vol. 13, 2003.
- [13] H.-Y. Lin, J.H. Huang, C.-C. Ma, “Vibration analysis of piezoelectric materials by optical methods”, IEEE `Transactions on Ultrasonics, Ferroelectrics, and Frequency Control, vol. 49, no. 8, 2002.

- [14] C.A.J. Putman, B.G.De Grooth, N.F. Van Hulst, J. Greve, "A detailed analysis of the optical beam deflection technique for use in atomic force microscopy", *Journal of Applied Physics*, vol. 72, no. 1, 1992.
- [15] Y. Ahn, H. Guckel, J.D. Zook, "Capacitive microbeam resonator design", *Journal of Micromechanics and Microengineering*, vol. 11, 2001.
- [16] J. Zhao, "Experimental Characterization of Dynamic Behaviour of Micromechined Mechanical Resonators", MSc Thesis, (2005) University of Manitoba, Canada.
- [17] G. Stemme, "Resonant silicon sensors", *Journal of Micromechanics and Microengineering*, vol. 1, 1991.
- [18] P. M. Zavracky *et al.*, "Microswitches and microrelays with a view toward microwave applications," *Int. J. of RF and Microwave Computer-Aided Eng.*, vol. 9, pp. 338–347, 1999.
- [19] J. Y. Park *et al.*, "Monolithically integrated micromachined RF MEMS capacitive switches," *Sensors*
- [20] J.-M. Huang *et al.*, "Mechanical design and optimization of capacitive micromachined switch," *Sensors and Actuators A*, vol. 93, pp. 273–285, 2001. S. Majumder *et al.*, "Study of contacts in an electrostatically actuated microswitch," *Sensors and Actuators A*, vol. 93, pp. 19–26, 2001.
- [21] T. Tinttunen, T. Veijola, H. Nieminen, V. Ermolov, and T. Ryh anen, "Static equivalent circuit model for a capacitive MEMS RF switch," in *Proceedings of MSM 2002*, (San Juan),
- [22] T. Veijola, T. Tinttunen, H. Nieminen, V. Ermolov, and T. Ryh anen, "Gas damping model for a RF MEMS switch and its dynamic characteristics," in *Proceedings of the International Microwave Symposium*, (Seattle, WA), June 2002.
- [23] T. Veijola and S. L ahteenm aki, "Electrical equivalent-circuit model for small-current electromechanic metal contact," in *Proceedings of the 16th European Conference on Circuit Theory and Design*, vol. 3, (Krakow), pp. 209–212, Sept. 2003.
- [24] <http://www.aplac.com>.

- [25] D. Hyman and M. Mehregany, Contact Physics of Gold Microcontacts for MEMS Switches, IEEE Transactions on Components and Packaging technologies, vol. 22, no.3, Sept. 1999, p. 357-364.
- [26] B.P. Gogoi and C.H. Mastrangelo, Adhesion Release and Yield Enhancement of Microstructures Using Pulsed Lorentz Forces, Journal of Microelectromechanical Systems, vol. 4, no. 4, december 1995.
- [27] F.D. Bannon, J.R. Clark and C.T.-C. Nguyen, High-Q HF Microelectromechanical Filters, IEEE Journal of Solid-State Circuits, vol.35, no.4, april 2000.
- [28] C. Bozler, R. Drangmeister, S. Du_y, M. Gouker, J. Knecht, L. Kushner, R. Parr, S. Rabe, L. Travis, MEMS microswitch arrays for recon_gurable distributed microwave components, Microwave Symposium Digest., 2000 IEEE MTT-S International, vol. 1, 2000
- [29] D.S. Greywall, Micromechanical RF Filters excited by the Lorentz Force, J. Micromech. Microeng., vol.9, 1999.
- [30] R.A. Mc Currie, Ferromagnetic Materials, Structure and Properties, Academic Press, 1994.
- [31] V. Milanovic, M. Maharbiz, A. Singh, B. Warneke, Z. Ningning, H.K. Chan,
- [32] K.S.J. Pister, Microrelays for batch transfer integration in RF systems, Micro Electro Mechanical Systems, 2000. MEMS 2000, Jan 2000.
- [33] J-W. Park, J.Y. Park, Y-H Joung and M.G. Allen, Fabrication of High Current and Low Prole Micromachined Inductor With Laminated Ni/Fe Core,
- [34] IEEE Transacions on Components and Packaging Technologies, vol.25, no.1, March 2002.
- [35] J.-M. Huang, K.M. Liew, C.H. Wong, S. Rajendran, M.J. Tan, A.Q. Liu, Mechanical design and optimization of capacitive micromachined switch, Sensors and Actuators A, no. 93, 2001.
- [36] M. G_eradin, D. Rixen, Mechanical Vibrations: Theory and Application to Structural Dynamics, 2nd edition, Wiley, NY, 1997.